

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: OHMI et al

Serial No.: 10/566,241

Filed: January 30, 2006

For: Microwave Plasma Processing Method, Microwave  
Plasma Processing Apparatus, And Its Plasma Head

Art Unit:

Examiner:

**PRELIMINARY AMENDMENT**

Mail Stop: Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

October 4, 2006

Sir:

The following amendments and remarks are respectfully requested in  
connection with the above-identified application as listed below and as set forth on  
the following pages:

Amendments to the Specification;

Amendments to the Claims;

Amendments to the Abstract; and

Remarks are included following the amendments.